

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Attorney Docket No. 50169/105/ENPO

In re patent application of

Wallace T.Y. TANG

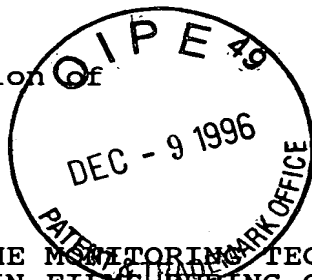
Serial No. 08/401,229

Filed: March 9, 1995

Group Art Unit: 2501

Examiner: J. Lee

For: IN-SITU REAL-TIME MONITORING TECHNIQUE AND APPARATUS FOR ENDPOINT DETECTION OF THIN FILMS DURING CHEMICAL/MECHANICAL POLISHING PLANARIZATION



TRANSMITTAL

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Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

Transmitted herewith is an Amendment in the above-captioned application. The fee has been calculated as shown below. (Small entity fees indicated in parentheses.)

CLAIMS AS AMENDED						
(1)	(2)	(3)	(4)	(5)	(6)	(7)
	Claims Remaining After Amendment		Highest Number Previously Paid For	Extra Claims	Rate	Fee
Total Claims	56	-	22	34	22.00	374.00
(Small Entity)					(11.00)	
Independent claims	12	-	7	6	80.00	240.00
(Small Entity)					(40.00)	
Multiple Dependent		-			260.00	
(Small Entity)					(130.00)	
Extension of Time	One Month		Two Months	Three Months		
Fee	\$110		\$390	\$930		
(Small Entity)	(\$55)		(\$195)	(\$465)		
Total						\$614.00

A check in the amount of the above Total Fee is attached. This amount is believed to be correct; however, the Commissioner is hereby authorized to charge any deficiency or credit any overpayment to Deposit Account No. 19-0741.

Respectfully submitted,

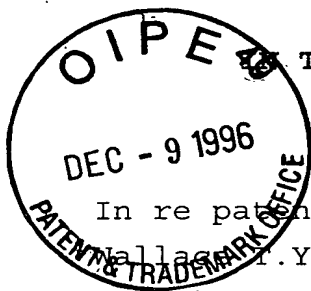
Date: December 9, 1996

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Y. TANG

Group Art Unit: 2501

Serial No. 08/401,229

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AMENDMENT AND REQUEST FOR RECONSIDERATION  
UNDER 37 C.F.R. § 1.111

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the outstanding Office Action mailed on  
September 9, 1996, please amend the above-identified application  
as follows:

IN THE CLAIMS

Please cancel claims 36-38.

Please add the following claims:

0 - 20. A chemical mechanical polisher for planarizing a  
film on a substrate comprising at least one light source that  
illuminates at least one section of the film on the substrate to  
create at least one reflected light signal received by a  
photodetector positioned in close proximity to the reflected  
light signal, which converts the reflected light signal into an  
electrical signal and transmits the electrical signal to an  
electrical slip ring, said electrical slip ring uncoupling the  
electrical signal from rotation and being operably connected to  
an analyzer that analyzes the electrical signal to monitor the  
progress of planarization.